

Notice of References Cited

Application/Control No.

09/705,507

Applicant(s)/Patent Under
Reexamination
JACOBS ET AL.

Examiner

Ryan J Hesseltine

Art Unit

2623

Page 1 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,137,896 A	10-2000	Chang et al.	382/118
	B	US-6,501,857 B1	12-2002	Gotsman et al.	382/224
	C	US-5,710,833	01-1998	Moghaddam et al.	382/228
	D	US-5,724,447	03-1998	Fukushima, Ikutoshi	382/211
	E	US-6,009,437 A	12-1999	Jacobs, David W.	707/102
	F	US-6,292,575 B1	09-2001	Bortolussi et al.	382/118
	G	US-6,466,685 B1	10-2002	Fukui et al.	382/115
	H	US-6,621,929 B1	09-2003	Lai et al.	382/217
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	WO 00/33240 A	06-2000	WIPO	Taylor et al.	G06K 9/00
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Belhumeur et al. "Eigenfaces vs. Fisherfaces: Recognition using class specific linear projection." Pattern Analysis and Machine Intelligence, IEEE Transactions on, Volume: 19, Issue: 7, July 1997. pp 711-720
	V	Nayar et al. "Dimensionality of illumination in appearance matching." Robotics and Automation, 1996. Proceedings., 1996 IEEE International Conference on, Volume: 2, 22-28 April 1996. pp 1326 - 1332
	W	Erturk et al. "3D model representation using spherical harmonics." Electronics Letters, Volume: 33, Issue: 11, 22 May 1997. pp 951 - 952
	X	Adini et al. "Face recognition: the problem of compensating for changes in illumination direction." Pattern Analysis and Machine Intelligence, IEEE Transactions on, Volume: 19, Issue: 7, July 1997. pp 721 - 732

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Notice of References Cited

Application/Control No.

09/705,507

Applicant(s)/Patent Under
Reexamination
JACOBS ET AL.

Examiner

Ryan J Hesseltine

Art Unit

2623

Page 2 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Hager et al. "Efficient region tracking with parametric models of geometry and illumination." Pattern Analysis and Machine Intelligence, IEEE Transactions on, Volume: 20, Issue: 10, Oct. 1998. pp 1025 - 1039
	V	Jacobs et al. "Comparing images under variable illumination." Computer Vision and Pattern Recognition, 1998. Proceedings. 1998 IEEE Computer Society Conference on, 23-25 June 1998. pp 610 - 617
	W	Chen et al. "In search of illumination invariants." Computer Vision and Pattern Recognition, 2000. Proceedings. IEEE Conference on, Volume: 1, 13-15 June 2000. pp 254 - 261
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.